

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Appln. of: Nixon et al.

Appln. No.: 10/693,425

Filed: October 24, 2003

For: BORON CARBIDE BASED CERAMIC
MATRIX COMPOSITES

Examiner: Group, Karl E.

Art Unit: 1755

Attorney Docket No: 4865-133

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98, and more particularly in accordance with 37 C.F.R. §1.97(c), Applicants hereby cite the following reference(s):

2000-256064 (Japan), September 19, 2000 – Translation

Vijay Vasant Pujar, *Processing and Microstructural Characterization of Reaction-Formed Silicon Carbide (RFSC) and Computer Simulations, X-Ray Diffraction and High Resolution Transmission Electron Microscopy of Stacking Faults in β -SiC*, Case Western Reserve University Dissertation, January 1997, pp. 38-51

Applicants are enclosing Form PTO-1449 (one sheet), along with a copy of each listed reference for which a copy is required under 37 C.F.R. §1.98(a)(2). As each of the listed references is in English, no further commentary is believed to be necessary, 37 C.F.R. §1.98(a)(3). Applicants respectfully request the Examiner's consideration of the above reference(s) and entry thereof into the record of this application.

By submitting this Statement, Applicants are attempting to fully comply with the duty of candor and good faith mandated by 37 C.F.R. §1.56. As such, this Statement is not intended to constitute an admission that any of the enclosed references, or other information referred to therein, constitutes "prior art" or is otherwise "material to patentability," as that phrase is defined in 37 C.F.R. §1.56(a).

Applicants have calculated a processing fee in the amount of \$180.00 to be due under 37 C.F.R. §1.17(p) in connection with the filing of this Statement. Applicants have enclosed a check covering this fee, or authorized charging the fee to a deposit account or credit card, as indicated in the Transmittal accompanying this Statement.

Respectfully submitted,

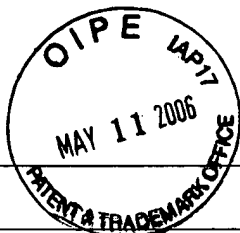
May 8, 2006
Date

Stephanie J. Felicetty
Stephanie J. Felicetty (Reg. No. 50,814)

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FORM PTO-1449	SERIAL NO. 10/693,425	CASE NO. 4865-133
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	FILING DATE October 24, 2003	GROUP ART UNIT 1755
(use several sheets if necessary)		APPLICANT(S): Nixon et al.

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER <small>Number-Kind Code (if known)</small>	DATE	NAME	CLASS/ SUBCLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER <small>Number-Kind Code (if known)</small>	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES OR NO
	B1 2000-256064 (translation)	9/19/00	Japan		Yes

EXAMINER INITIAL	OTHER ART – NON PATENT LITERATURE DOCUMENTS <small>(Include name of author, title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date page(s), volume-issue number(s), publisher, city and/or country where published.)</small>	
	B2	Vijay Vasant Pujar, <i>Processing and Microstructural Characterization of Reaction-Formed Silicon Carbide (RFSC) and Computer Simulations, X-Ray Diffraction and High Resolution Transmission Electron Microscopy of Stacking Faults in β-SiC</i> , Case Western Reserve University Dissertation, January 1997, pp. 38-51

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.